

Jun-Bo Yoon

List of Publications by Year in descending order

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195
papers

4,287
citations

126907

33
h-index

144013

57
g-index

198
all docs

198
docs citations

198
times ranked

4355
citing authors

#	ARTICLE	IF	CITATIONS
1	A robust superhydrophobic and superoleophobic surface with inverse-trapezoidal microstructures on a large transparent flexible substrate. <i>Soft Matter</i> , 2010, 6, 1401.	2.7	319
2	A sub-1-volt nanoelectromechanical switching device. <i>Nature Nanotechnology</i> , 2013, 8, 36-40.	31.5	166
3	Self-cleaning hybrid energy harvester to generate power from raindrop and sunlight. <i>Nano Energy</i> , 2015, 12, 636-645.	16.0	166
4	Microlens array diffuser for a light-emitting diode backlight system. <i>Optics Letters</i> , 2006, 31, 3016.	3.3	147
5	Fabrication and characterization of a nanoelectromechanical switch with 15-nm-thick suspension air gap. <i>Applied Physics Letters</i> , 2008, 92, .	3.3	130
6	CMOS-compatible surface-micromachined suspended-spiral inductors for multi-GHz silicon RF ICs. <i>IEEE Electron Device Letters</i> , 2002, 23, 591-593.	3.9	123
7	Performance-enhanced triboelectric nanogenerator enabled by wafer-scale nanogrates of multistep pattern downscaling. <i>Nano Energy</i> , 2017, 35, 415-423.	16.0	120
8	Surface micromachined solenoid on-Si and on-glass inductors for RF applications. <i>IEEE Electron Device Letters</i> , 1999, 20, 487-489.	3.9	107
9	Lock-and-Key-Geometry Effect of Patterned Surfaces: Wettability and Switching of Adhesive Force. <i>Small</i> , 2009, 5, 90-94.	10.0	104
10	NEMS switch with 30nm-thick beam and 20nm-thick air-gap for high density non-volatile memory applications. <i>Solid-State Electronics</i> , 2008, 52, 1578-1583.	1.4	94
11	Shape-controlled, high fill-factor microlens arrays fabricated by a 3D diffuser lithography and plastic replication method. <i>Optics Express</i> , 2004, 12, 6366.	3.4	93
12	3-D construction of monolithic passive components for RF and microwave ICs using thick-metal surface micromachining technology. <i>IEEE Transactions on Microwave Theory and Techniques</i> , 2003, 51, 279-288.	4.6	88
13	Hermetically Sealed Inductor-Capacitor (LC) Resonator for Remote Pressure Monitoring. <i>Japanese Journal of Applied Physics</i> , 1998, 37, 7124-7128.	1.5	80
14	60-GHz CPW-fed post-supported patch antenna using micromachining technology. <i>IEEE Microwave and Wireless Components Letters</i> , 2005, 15, 635-637.	3.2	75
15	Simple liquid crystal display backlight unit comprising only a single-sheet micropatterned polydimethylsiloxane (PDMS) light-guide plate. <i>Optics Letters</i> , 2007, 32, 2665.	3.3	67
16	A simple and effective lift-off with positive photoresist. <i>Journal of Micromechanics and Microengineering</i> , 2005, 15, 2136-2140.	2.6	65
17	Spontaneous Lamellar Alignment in Thickness-Modulated Block Copolymer Films. <i>Advanced Functional Materials</i> , 2009, 19, 2584-2591.	14.9	63
18	Nanoelectromechanical (NEM) relays integrated with CMOS SRAM for improved stability and low leakage. , 2009, , .		58

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19	Experimental Analysis of the Effect of Metal Thickness on the Quality Factor in Integrated Spiral Inductors for RF ICs. IEEE Electron Device Letters, 2004, 25, 76-79.	3.9	57
20	Optically Selective Microlens Photomasks Using Self-Assembled Smectic Liquid Crystal Defect Arrays. Advanced Materials, 2010, 22, 2416-2420.	21.0	57
21	A simple and effective fabrication method for various 3D microstructures: backside 3D diffuser lithography. Journal of Micromechanics and Microengineering, 2008, 18, 125015.	2.6	52
22	Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film. Advanced Functional Materials, 2018, 28, 1804721.	14.9	50
23	High-Performance Copper Oxide Visible-Light Photodetector via Grain-Structure Model. Scientific Reports, 2019, 9, 7334.	3.3	50
24	A thermal inkjet printhead with a monolithically fabricated nozzle plate and self-aligned ink feed hole. Journal of Microelectromechanical Systems, 1999, 8, 229-236.	2.5	48
25	Versatile Transfer of an Ultralong and Seamless Nanowire Array Crystallized at High Temperature for Use in High-Performance Flexible Devices. ACS Nano, 2017, 11, 1520-1529.	14.6	48
26	A high fill-factor infrared bolometer using micromachined multilevel electrothermal structures. IEEE Transactions on Electron Devices, 1999, 46, 1489-1491.	3.0	46
27	Metal-oxide-semiconductor field effect transistor humidity sensor using surface conductance. Applied Physics Letters, 2012, 100, .	3.3	45
28	Fabrication of polymeric large-core waveguides for optical interconnects using a rubber molding process. IEEE Photonics Technology Letters, 2000, 12, 62-64.	2.5	44
29	One-chip electronic detection of DNA hybridization using precision impedance-based CMOS array sensor. Biosensors and Bioelectronics, 2010, 26, 1373-1379.	10.1	43
30	Chemo-Mechanically Operating Palladium-Polymer Nanograting Film for a Self-Powered H ₂ Gas Sensor. ACS Nano, 2020, 14, 16813-16822.	14.6	40
31	Monolithic Fabrication of Electroplated Solenoid Inductors Using Three-Dimensional Photolithography of a Thick Photoresist. Japanese Journal of Applied Physics, 1998, 37, 7081-7085.	1.5	39
32	High Throughput Ultralong (20 cm) Nanowire Fabrication Using a Wafer-Scale Nanograting Template. Nano Letters, 2013, 13, 3978-3984.	9.1	38
33	Monolithic high-Q overhang inductors fabricated on silicon and glass substrates. , 0, , .		37
34	A One-Step Route to a Perfectly Ordered Wafer-Scale Microbowl Array for Size-Dependent Superhydrophobicity. Small, 2008, 4, 211-216.	10.0	37
35	Electrowetting on a Polymer Microlens Array. Langmuir, 2010, 26, 12443-12447.	3.5	36
36	A conventional route to scalable morphology-controlled regular structures and their superhydrophobic/hydrophilic properties for biochips application. Lab on A Chip, 2009, 9, 2140.	6.0	33

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37	Analytical Modeling and Thermodynamic Analysis of Robust Superhydrophobic Surfaces with Inverse-Trapezoidal Microstructures. <i>Langmuir</i> , 2010, 26, 17389-17397.	3.5	33
38	Liquid-based electrostatic energy harvester with high sensitivity to human physical motion. <i>Smart Materials and Structures</i> , 2011, 20, 125012.	3.5	33
39	An Extremely Low Contact-Resistance MEMS Relay Using Meshed Drain Structure and Soft Insulating Layer. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 204-212.	2.5	32
40	An Electrostatically Actuated Stacked-Electrode MEMS Relay With a Levering and Torsional Spring for Power Applications. <i>Journal of Microelectromechanical Systems</i> , 2012, 21, 1209-1217.	2.5	32
41	3-terminal nanoelectromechanical switching device in insulating liquid media for low voltage operation and reliability improvement. , 2009, , .		31
42	Parallel-Plate MEMS Variable Capacitor With Superior Linearity and Large Tuning Ratio Using a Levering Structure. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 1345-1354.	2.5	30
43	Batch-fabricated CO gas sensor in large-area (8-inch) with sub-10 mW power operation. <i>Sensors and Actuators B: Chemical</i> , 2019, 289, 153-159.	7.8	28
44	MEMS-Based Tunable LC Bandstop Filter With an Ultra-Wide Continuous Tuning Range. <i>IEEE Microwave and Wireless Components Letters</i> , 2009, 19, 710-712.	3.2	27
45	A simple breathing rate-sensing method exploiting a temporarily condensed water layer formed on an oxidized surface. <i>Applied Physics Letters</i> , 2015, 106, .	3.3	27
46	A CMOS label-free DNA sensor using electrostatic induction of molecular charges. <i>Biosensors and Bioelectronics</i> , 2012, 31, 343-348.	10.1	26
47	Geometrically Structured Nanomaterials for Nanosensors, NEMS, and Nanosieves. <i>Advanced Materials</i> , 2020, 32, e1907082.	21.0	26
48	High-performance electroplated solenoid-type integrated inductor (SI/sup 2I) for RF applications using simple 3D surface micromachining technology. , 0, , .		25
49	Complementary Dual-Contact Switch Using Soft and Hard Contact Materials for Achieving Low Contact Resistance and High Reliability Simultaneously. <i>Journal of Microelectromechanical Systems</i> , 2013, 22, 846-854.	2.5	25
50	CMOS capacitive biosensor with enhanced sensitivity for label-free DNA detection. , 2012, , .		24
51	A Complementary Dual-Contact MEMS Switch Using a "Zipping" Technique. <i>Journal of Microelectromechanical Systems</i> , 2014, 23, 710-718.	2.5	24
52	An ultra-low voltage MEMS switch using stiction-recovery actuation. <i>Journal of Micromechanics and Microengineering</i> , 2013, 23, 045022.	2.6	23
53	>1000-Fold Lifetime Extension of a Nickel Electromechanical Contact Device via Graphene. <i>ACS Applied Materials & Interfaces</i> , 2018, 10, 9085-9093.	8.0	23
54	Edge-lit LCD backlight unit for 2D local dimming. <i>Optics Express</i> , 2018, 26, 20802.	3.4	23

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55	Fabrication of a uniform microlens array over a large area using self-aligned diffuser lithography (SADL). Journal of Micromechanics and Microengineering, 2012, 22, 045002.	2.6	22
56	Use of a Columnar Metal Thin Film as a Nanosieve with Sub-10 nm Pores. Advanced Materials, 2012, 24, 4408-4413.	21.0	22
57	High-performance three-dimensional on-chip inductors fabricated by novel micromachining technology for RF MMIC. , 0, , .		21
58	Mechanically Operated Random Access Memory (MORAM) Based on an Electrostatic Microswitch for Nonvolatile Memory Applications. IEEE Transactions on Electron Devices, 2008, 55, 2785-2789.	3.0	21
59	Material-Independent Nanotransfer onto a Flexible Substrate Using Mechanical-Interlocking Structure. ACS Nano, 2018, 12, 4387-4397.	14.6	21
60	Nanowire Mechanical Switch with a Built-in Diode. Small, 2010, 6, 1197-1200.	10.0	20
61	Silicon Photonic Wire Filter Using Asymmetric Sidewall Long-Period Waveguide Grating in a Two-Mode Waveguide. IEEE Photonics Technology Letters, 2008, 20, 520-522.	2.5	19
62	Actively transparent display with enhanced legibility based on an organic light-emitting diode and a cholesteric liquid crystal blind panel. Optics Express, 2013, 21, 10358.	3.4	19
63	Multi-resonant energy harvester exploiting high-mode resonances frequency down-shifted by a flexible body beam. Applied Physics Letters, 2012, 101, .	3.3	18
64	Stress-engineered palladium nanowires for wide range (0.1%–3.9%) of H ₂ detection with high durability. Nanoscale, 2019, 11, 16317-16326.	5.6	18
65	Micromachined CPW-Fed Suspended Patch Antenna for 77 GHz Automotive Radar Applications. , 0, , .		17
66	Multilevel microstructure fabrication using single-step 3D photolithography and single-step electroplating. , 1998, , .		16
67	A Highly Reliable MEMS Relay With Two-Step Spring System and Heat Sink Insulator for High-Power Switching Applications. Journal of Microelectromechanical Systems, 2016, 25, 217-226.	2.5	16
68	Nanotransplantation Printing of Crystallographic-Orientation-Controlled Single-Crystalline Nanowire Arrays on Diverse Surfaces. ACS Nano, 2017, 11, 11642-11652.	14.6	16
69	Aligned CuO nanowire array for a high performance visible light photodetector. Scientific Reports, 2022, 12, 2284.	3.3	16
70	3-D lithography and metal surface micromachining for RF and microwave MEMS. , 0, , .		15
71	A Highly Reliable Two-Axis MEMS Relay Demonstrating a Novel Contact Refresh Method. Journal of Microelectromechanical Systems, 2015, 24, 1495-1502.	2.5	15
72	Modeling, Design, Fabrication, and Demonstration of a Digital Micromirror With Interdigitated Cantilevers. Journal of Microelectromechanical Systems, 2009, 18, 1382-1395.	2.5	13

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73	A mechanical and electrical transistor structure (METS) with a sub-2 nm nanogap for effective voltage scaling. <i>Nanoscale</i> , 2014, 6, 7799.	5.6	13
74	Wireless and Linear Hydrogen Detection up to 4% with High Sensitivity through Phase-Transition-Inhibited Pd Nanowires. <i>ACS Nano</i> , 2022, 16, 11957-11967.	14.6	13
75	A low-voltage two-axis electromagnetically actuated micromirror with bulk silicon mirror plates and torsion bars. , 0, , .		12
76	Fabrication of three-dimensional SiC-based ceramic micropatterns using a sequential micromolding-and-pyrolysis process. <i>Microelectronic Engineering</i> , 2006, 83, 2475-2481.	2.4	12
77	An insulating liquid environment for reducing adhesion in a microelectromechanical system. <i>Applied Physics Letters</i> , 2011, 99, 113516.	3.3	12
78	High-Performance Hybrid Complementary Logic Inverter through Monolithic Integration of a MEMS Switch and an Oxide TFT. <i>Small</i> , 2015, 11, 1390-1395.	10.0	12
79	Nanomechanical Encoding Method Using Enhanced Thermal Concentration on a Metallic Nanobridge. <i>ACS Nano</i> , 2017, 11, 7781-7789.	14.6	12
80	A new monolithic microbiosensor for whole blood analysis. <i>Sensors and Actuators A: Physical</i> , 2002, 95, 108-113.	4.1	11
81	Performance comparison of 5GHz VCOs integrated by CMOS compatible high Q MEMS inductors. , 0, , .		11
82	A 3-D planar microlens for an effective monolithic optical interconnection system. <i>IEEE Photonics Technology Letters</i> , 2006, 18, 814-816.	2.5	11
83	Design and fabrication of a micropatterned polydimethylsiloxane (PDMS) light-guide plate for sheet-less LCD backlight unit. <i>Journal of the Society for Information Display</i> , 2008, 16, 329-335.	2.1	11
84	An effective light-extracting microstructure for a single-sheet backlight unit for liquid crystal display. <i>Journal of Micromechanics and Microengineering</i> , 2012, 22, 095006.	2.6	11
85	Transparent conducting hybrid thin films fabricated by layer-by-layer assembly of single-wall carbon nanotubes and conducting polymers. <i>Applied Physics A: Materials Science and Processing</i> , 2012, 108, 305-311.	2.3	11
86	Ultra-low voltage MEMS switch using a folded hinge structure. <i>Micro and Nano Systems Letters</i> , 2014, 2, .	3.7	11
87	Electrostatic micro-actuator with a pre-charged series capacitor: modeling, design, and demonstration. <i>Journal of Micromechanics and Microengineering</i> , 2014, 24, 065012.	2.6	11
88	Integration of a Carbon Nanotube Network on a Microelectromechanical Switch for Ultralong Contact Lifetime. <i>ACS Applied Materials & Interfaces</i> , 2019, 11, 18617-18625.	8.0	11
89	Monolithic integration of 3-D electroplated microstructures with unlimited number of levels using planarization with a sacrificial metallic mold (PSMM). , 1999, , .		10
90	High-Q, tunable-gap MEMS variable capacitor actuated with an electrically floating plate. , 2008, , .		10

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91	Use of nanoporous columnar thin film in the wafer-level packaging of MEMS devices. Journal of Micromechanics and Microengineering, 2010, 20, 045002.	2.6	10
92	High performance microshutter device with space-division modulation. Journal of Micromechanics and Microengineering, 2010, 20, 075030.	2.6	10
93	Modeling, fabrication and demonstration of a rib-type cantilever switch with an extended gate electrode. Journal of Micromechanics and Microengineering, 2011, 21, 115009.	2.6	10
94	An autonomous CMOS hysteretic sensor for the detection of desorption-free DNA hybridization. Biosensors and Bioelectronics, 2011, 26, 4591-4595.	10.1	10
95	Fabrication of a membrane filter with controlled pore shape and its application to cell separation and strong single cell trapping. Journal of Micromechanics and Microengineering, 2015, 25, 105007.	2.6	10
96	Investigation of the Nanoparticle Electrical Contact Lubrication in MEMS Switches. Journal of Microelectromechanical Systems, 2017, 26, 1417-1427.	2.5	10
97	A high-performance MEMS transformer for silicon RF ICS. , 0, , .		9
98	A low loss MEMS transmission line with shielded ground. , 0, , .		9
99	MEMS variable capacitor with superior linearity and large tuning ratio by moving the plate to the increasing-gap direction. , 2011, , .		9
100	A trans-scaled nanofabrication using 3D diffuser lithography, metal molding and nano-imprinting. Journal of Micromechanics and Microengineering, 2011, 21, 045025.	2.6	9
101	Perfectly Aligned, Airâ€Suspended Nanowire Array Heater and Its Application in an Alwaysâ€On Gas Sensor. Advanced Functional Materials, 2020, 30, 2004448.	14.9	9
102	Realization of Nanolene: A Planar Array of Perfectly Aligned, Airâ€Suspended Nanowires. Small, 2020, 16, e1906845.	10.0	9
103	MEMS Variable Capacitor Actuated with an Electrically Floating Plate. , 2007, , .		8
104	A new approach to control a deflection of an electroplated microstructure: dual current electroplating methods. Journal of Micromechanics and Microengineering, 2013, 23, 055016.	2.6	8
105	A review of geometric and structural design for reliable flexible electronics. Journal of Micromechanics and Microengineering, 2021, 31, 074001.	2.6	8
106	A Dram-Like Mechanical Non-Volatile Memory. , 2007, , .		7
107	56.2: A New Reflective-type Transparent Display Using Cholesteric Liquid Crystal. Digest of Technical Papers SID International Symposium, 2010, 41, 838.	0.3	7
108	A Low Contact Resistance 4-Terminal Mems Relay: Theoretical Analysis, Design, and Demonstration. Journal of Microelectromechanical Systems, 2018, 27, 497-505.	2.5	7

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109	Utilizing mechanical adhesion force as a high contact force in a MEMS relay. Sensors and Actuators A: Physical, 2021, 331, 112894.	4.1	7
110	A monolithic thermal inkjet printhead utilizing electrochemical etching and two-step electroplating techniques. , 0, , .		6
111	A surface-micromachined tunable microgyroscope. , 0, , .		6
112	A disposable DNA sample preparation microfluidic chip for nucleic acid probe assay. , 0, , .		6
113	Pâ€73: A Novel LCD Backlight Unit using a Lightâ€guide Plate with High Fillâ€factor Microlens Array and a Conical Microlens Array Sheet. Digest of Technical Papers SID International Symposium, 2007, 38, 465-468.	0.3	6
114	Sloping profile and pattern transfer to silicon by shape-controllable 3-D lithography and ICP. Sensors and Actuators A: Physical, 2007, 139, 281-286.	4.1	6
115	Indium Tin Oxide (ITO) Transparent MEMS Switches. , 2009, , .		6
116	Mechanical Reliability of a Digital Micromirror With Interdigitated Cantilevers. Journal of Microelectromechanical Systems, 2010, 19, 1197-1206.	2.5	6
117	Mass-Producibile Polydimethylsiloxane (PDMS) Frontlight Unit (FLU) for Reflective Displays. Journal of Display Technology, 2011, 7, 526-531.	1.2	6
118	Adhesion Force Change by Electrowetting on a Polymer Microlens Array. Journal of Adhesion Science and Technology, 2012, 26, 2079-2086.	2.6	6
119	An electrostatic micromechanical biosensor for electrical detection of label-free DNA. Applied Physics Letters, 2012, 100, 163701.	3.3	6
120	Voltage-Controlled Q Response Tuning in a Parallel Plate MEMS Variable Capacitor. Journal of Microelectromechanical Systems, 2013, 22, 1403-1413.	2.5	6
121	Increasing Capacitance and Self-Resonant Frequency of the MEMS Switched Capacitor Using High- κ TiO_2 and SU-8 Bridged Beam Structure. Journal of Microelectromechanical Systems, 2015, 24, 1006-1015.	2.5	6
122	Design and fabrication of micromachined internal combustion engine as a power source for microsystems. , 0, , .		5
123	Fabrication of a large-scale Ni stamp using a multi-level SU-8 photoresist mold for advanced printed circuit board manufacturing. Journal of Micromechanics and Microengineering, 2011, 21, 065026.	2.6	5
124	Highly reliable MEMS relay with two-step spring system and heat sink insulator for power applications. , 2015, , .		5
125	Effect of excitation point on surface phonon fields in phononic crystals in real- and k-space. Journal of Applied Physics, 2015, 117, .	2.5	5
126	P-72: Ultra-thin Edge Type Single Sheet Backlight Unit for Seamless Two-dimensional Local Dimming. Digest of Technical Papers SID International Symposium, 2016, 47, 1406-1408.	0.3	5

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127	Highly aligned suspended nanowire array for self-heating type gas sensors. , 2017, , .		5
128	Realization of large-scale sub-10Ånm nanogratings using a repetitive wet-chemical oxidation and etching technique. Micro and Nano Systems Letters, 2017, 5, .	3.7	5
129	Mass-producible structural design and fabrication method for a slim light-guide plate having inverse-trapezoidal light out-couplers. Journal of Micromechanics and Microengineering, 2019, 29, 035001.	2.6	5
130	Integration of Gold Nanoparticle"Carbon Nanotube Composite for Enhanced Contact Lifetime of Microelectromechanical Switches with Very Low Contact Resistance. ACS Applied Materials & Interfaces, 2021, 13, 16959-16967.	8.0	5
131	Electro-Thermally Actuated Non-Volatile Mechanical Memory With CMOS-Level Operation Voltage and Low Contact Resistance. Journal of Microelectromechanical Systems, 2022, 31, 87-96.	2.5	5
132	Electrostatic digital micromirror using interdigitated cantilevers. , 0, , .		4
133	Linearly variable inductor with RF MEMS switches to enlarge a continuous tuning range. , 2009, , .		4
134	Novel buried inverse-trapezoidal micropattern for dual-sided light extracting backlight unit. Optics Express, 2014, 22, 32440.	3.4	4
135	Signal Power-Insensitive Analog MEMS Tunable Capacitor by Immobilizing the Movable Plates. Journal of Microelectromechanical Systems, 2015, 24, 1545-1556.	2.5	4
136	Carbon nanotubes network contact lubrication for highly reliable MEMS switch. , 2017, , .		4
137	A Proactive Plastic Deformation Method for Fine-Tuning of Metal-Based MEMS Devices After Fabrication. Journal of Microelectromechanical Systems, 2018, 27, 1124-1134.	2.5	4
138	4 W Power MEMS Relay With Extremely Low Contact Resistance: Theoretical Analysis, Design and Demonstration. Journal of Microelectromechanical Systems, 2020, 29, 1304-1313.	2.5	4
139	Micromachined CPW-fed suspended patch antenna for 77 GHz automotive radar applications. , 2005, , .		3
140	3D diffuser lithography : a novel method to fabricate various rounded microstructures. , 0, , .		3
141	A New Three-Dimensional Lithography Using Polymer Dispersed Liquid Crystal (PDLC) Films. , 0, , .		3
142	Exchangeable self-curable liquid gate dielectric embedded field effect transistor. Applied Physics Letters, 2010, 97, .	3.3	3
143	Modeling, fabrication and demonstration of an electrostatic actuator with a coplanar pre-charged electrode. Journal of Micromechanics and Microengineering, 2011, 21, 085012.	2.6	3
144	High-performance MEMS relay using a stacked-electrode structure and a levering and torsional spring for power applications. , 2012, , .		3

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145	Improvement of hot switching lifetime in MEMS DC switches using a drain voltage-sustaining capacitor. , 2013, , .		3
146	Three-dimensional (3-D) reshaping technique in MEMS devices by solely electrical control with ultrafine tuning resolution. , 2014, , .		3
147	P-67: Wide Bandwidth Reflective Microshutter Blind Panel for Transparent Organic Light-Emitting Diode Display. Digest of Technical Papers SID International Symposium, 2016, 47, 1389-1391.	0.3	3
148	4-Terminal MEMS relay with an extremely low contact resistance employing a novel one-contact design. , 2017, , .		3
149	First Lateral Contact Probing of $55\text{-}\mu\text{m}$ Fine Pitch Micro-Bumps. Journal of Microelectromechanical Systems, 2018, 27, 1114-1123.	2.5	3
150	An investigation of surficial conduction heat loss in perfectly aligned micro-wire array. Applied Physics Letters, 2019, 115, .	3.3	3
151	Ultra-Sensitive Strain Sensor Using High Density Self-Aligned Nano-Cracks. , 2020, , .		3
152	A Self-Powered Wireless Gas Sensor Node Based on Photovoltaic Energy Harvesting. , 2021, , .		3
153	Fabrication of a Single Crystal Silicon Substrate for AM-LCD Using Vertical Etching of (110) Silicon. Materials Research Society Symposia Proceedings, 1995, 377, 859.	0.1	2
154	A high fill-factor IR bolometer using multi-level electrothermal structures. , 0, , .		2
155	A Highly Flexible Superhydrophobic Microlens Array with Small Contact Angle Hysteresis for Droplet-Based Microfluidics. , 2009, , .		2
156	An electrostatic energy harvester exploiting variable-area water electrode by respiration. , 2015, , .		2
157	Unconventional Use of a Photoresist as a Nitrogen Gas Generator Forming Transparent Dome-Shaped Microcavities. Advanced Engineering Materials, 2016, 18, 559-566.	3.5	2
158	Micro and Nanoelectromechanical Contact Switches for Logic, Memory, and Power Applications. KAIST Research Series, 2016, , 65-117.	1.5	2
159	Palladium Hydrogen Sensor with Perfectly Aligned and Highly Uniform Nanogap Arrays. , 2019, , .		2
160	A New Monolithic Inkjet Printhead Using Single Crystalline Silicon For A Heating Resistor. , 1998, , .		1
161	Self-assembled monolayer-assisted thin metal polishing for fabricating uniform 3D microstructures. Journal of Micromechanics and Microengineering, 2005, 15, 1027-1032.	2.6	1
162	High fill-factor micromirror array and its fabrication process. , 0, , .		1

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163	High Fill-Factor Paraboloidal Microlens Arrays. , 2006, , .		1
164	A new method of driving an AMOLED with MEMS switches. Proceedings of the IEEE International Conference on Micro Electro Mechanical Systems (MEMS), 2008, , .	0.0	1
165	3.4: Invited Paper: A Novel Use of MEMS Switches in Driving AMOLED. Digest of Technical Papers SID International Symposium, 2008, 39, 13.	0.3	1
166	Maneuvering actuation voltage of a electrostatic MEMS switch with a new coplanar pre-charged electrode. , 2010, , .		1
167	Fast and robust cantilever switch with suppressed bouncing for ic applications. , 2011, , .		1
168	A newly designed curved beam microshutter display device with high aperture ratio. , 2013, , .		1
169	A surface conductance based fully integrated standard CMOS humidity sensor without post-processing. , 2015, , .		1
170	P-70: Light Shifted Light-guide Plate for Simple Multi-view Spatial/Temporal Hybrid Autostereoscopic Display. Digest of Technical Papers SID International Symposium, 2016, 47, 1399-1401.	0.3	1
171	Efforts toward ideal microelectromechanical switches. , 2017, , .		1
172	MEMS packaging method without any heating or external force using adhesive bonding assisted by capillary force. , 2017, , .		1
173	High performance flexible tactile sensor array using a large area plastic nano-grating substrate. , 2017, , .		1
174	Self-Powered, Ultra-Reliable Hydrogen Sensor Exploiting Chemomechanical Nano-Transducer and Solar-Cell. , 2019, , .		1
175	Always-On Gas Sensors: Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor (Adv. Funct. Mater. 39/2020). Advanced Functional Materials, 2020, 30, 2070264.	14.9	1
176	4 W Dual-Contact Material MEMS Relay with a Contact Force Maximizing Structure. , 2020, , .		1
177	A high efficiency 3D planar microlens for monolithic optical interconnection system. , 2005, , .		0
178	Stiction-free cantilevers with rounded cross-section. , 0, , .		0
179	Novel voltage controlled spatial modulation method for digital microshutter display with high performance. , 2009, , .		0
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